

THE INVENTION CLAIMED IS:

1. A standardized facilities box comprising:
a box;
a mechanism for mounting the box to a support
pedestal of a semiconductor fabrication facility; and
one or more mechanisms for selectively coupling any
one of a set of add-on features within the box.

2. The standardized facilities box of claim 1
further comprising an add-on feature coupled to the one or
more mechanisms for selectively coupling.

3. The standardized facilities box of claim 2
wherein the add-on feature comprises a partition.

4. The standardized facilities box of claim 2
wherein the add-on feature comprises a document storage
compartment.

5. The standardized facilities box of claim 2
wherein the add-on feature comprises a sensor and a warning
indicator.

6. The standardized facilities box of claim 2
wherein the add-on feature comprises an automatic lockout
mechanism.

7. The standardized facilities box of claim 2
wherein the add-on feature comprises a tool storage
mechanism.

8. The standardized facilities box of claim 2
wherein the add-on feature comprises a support leg.

9. The standardized facilities box of claim 2
wherein the add-on feature comprises a bridge mechanism
adapted to interface between the mechanism for mounting the
box and a support pedestal.

10. The standardized facilities box of claim 2 wherein the add-on feature comprises a mechanical locating mechanism for a facilities connection.

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11. The standardized facilities box of claim 2 wherein the add-on feature comprises another standardized facilities box comprising:

a box;

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a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and

one or more mechanisms for selectively coupling any one of a set of add-on features to the box.

12. The standardized facilities box of claim 2 wherein the add-on feature comprises an openable cover.

13. The standardized facilities box of claim 2 wherein the add-on feature comprises floor lighting.

14. The standardized facilities box of claim 2 wherein the add-on feature comprises a lifting mechanism adapted to lift and/or lower the box into or from a position for mounting the box to a support pedestal.

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15. The standardized facilities box of claim 2 wherein the add-on feature comprises a lifting mechanism adapted to lift and/or lower an item to or from the box.

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16. A facilities box comprising:

a box;

a mechanism for mounting the box to a raised floor tile of a semiconductor fabrication facility; and

a support leg coupled to the box for supporting the

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box.

17. A facilities box comprising:

a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and

5 a lifting mechanism coupled to the box adapted to lift and/or lower the box into or from a position for mounting the box to a support pedestal.

18. A facilities box comprising:

10 a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and

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20449 a lifting mechanism adapted to lift and/or lower an item to or from the box.

19. A facilities box comprising:

a box adapted to house facilities connections therein;

20 a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and a sensor.

20. A facilities box comprising:

25 a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and an exhaust mechanism.

30 21. A facilities box comprising:

a box adapted to house facilities connections therein;

35 a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; a cover coupled to the box; and a lockout mechanism adapted to lock the cover of the box.

22. The facilities box of claim 21 wherein the
lockout mechanism is a lockout tag out mechanism.

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23. A method of standardizing a semiconductor
fabrication facility, comprising:

indicating a location within a fabrication facility
for installing a facilities box;

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providing a standardized facilities box having a
mechanism for selectively coupling any one of a set of add-on
features to the standardized facilities box;

providing a plurality of add-on features; and

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specifying which add-on feature should be
selectively coupled to which selective coupling mechanism of
the standardized facilities box.

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